

Title (en)

MICROWAVE PLASMA GENERATING DEVICES AND PLASMA TORCHES

Title (de)

GERÄTE ZUR ERZEUGUNG VON MIKROWELLENPLASMA UND PLASMABRENNER

Title (fr)

DISPOSITIFS GENERATEURS DE PLASMA MICRO-ONDES ET TORCHES A PLASMA

Publication

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Application

EP 08837221 A 20080916

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- FR 0757719 A 20070920

Abstract (en)

[origin: WO2009047441A1] The invention relates to a plasma generating device that comprises at least one very high frequency source (> 100 MHz) connected via an impedance adaptation device to an elongated conductor attached on a dielectric substrate, at least one means for cooling said conductor, and at least one gas supply in the vicinity of the dielectric substrate on a side opposite to that bearing the conductor. The invention also relates to plasma torches using said device.

IPC 8 full level

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